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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

TO:

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

FROM:

Tung & Associates

838 West Long Lake Road - Suite 120

Bloomfield Hills, MI 48302

DATE:

28 April 2004

REF:

Appellant

: Chen et al

Filing Date

: 15 October 2001

Serial No.

: 09/978,420

Att'y No.

: 67,200-409; TSMC 00-661

Art Unit

: 2815

Examiner

: N. Drew Richards

Title

: Microelectronic Fabrication With Upper Lying Aluminum Fuse

Layer in Copper Interconnect Semiconductor Technology and

Method for Fabrication Thereof

AMENDMENT AND RESPONSE TO OFFICE ACTION

Sir:

In response to an office action mailed on 24 March 2004, please consider the following amendments and remarks pertaining to the above referenced application.

There are no amendments to the specification. Amendments to the claims are found within a Listing of the Claims that begins on page 2 of this paper. There are no amendments to the drawings. Remarks begin on page 4 of this paper.

CERTIFICATE OF MAILING

Kathy Dixon